

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

HAN et al.

Atty. Ref.: 4290-4; Confirmation No. 5867

Appl. No. 10/690,665

TC/A.U. 1763

Filed: October 23, 2003

Examiner: G. Goudreau

For: METHOD FOR AVOIDING POLYSILICON FILM OVER ETCH ABNORMAL

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September 27, 2007

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

In response to the Office Action dated 06/27/2007, please amend the above-identified application as shown below: